



Docket No. 0068-0399-0

IN RE APPLICATION OF: Masakazu KANECHIKA, et al.

SERIAL NO: 09/420,524

FILED: October 18, 1999

FOR: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE AND SEMICONDUCTOR DEVICE

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Transmitted herewith is an **Amendment and Request for Reconsideration w/Marked-Up Copy** in the above-identified application.

- ☐ No additional fee is required
- ☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.
- ☒ Additional documents filed herewith: **Request for Extension of Time (ONE-MONTH)**

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS	RATE	CALCULATIONS
TOTAL	48	MINUS	38	10	x \$18 =	\$180.00
INDEPENDENT	15	MINUS	11	4	x \$84 =	\$336.00
		<input type="checkbox"/> MULTIPLE DEPENDENT CLAIMS			+ \$280 =	\$0.00
		TOTAL OF ABOVE CALCULATIONS				\$516.00
		<input type="checkbox"/> Reduction by 50% for filing by Small Entity				\$0.00
		<input type="checkbox"/> Recordation of Assignment			+ \$40 =	\$0.00
		TOTAL				\$516.00

- ☒ A check in the amount of **\$626.00** is attached.
- ☒ Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- ☒ If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

Masakazu KANECHIKA, et al.

: GROUP ART UNIT: 2823

SERIAL NO.: 09/420,524

:

FILED: October 18, 1999

: EXAMINER: J. GARCIA

FOR: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE AND
SEMICONDUCTOR DEVICE

AMENDMENT AND REQUEST FOR RECONSIDERATION

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

In response to the Office Action dated July 18, 2002, the period for response
having been extended to November 18, 2002, by a Request for Extension of Time filed
herewith, please reconsider the application in view of the following amendment and remarks.

IN THE CLAIMS

Please amend the Claims as follows:

1. (Amended) A method for manufacturing a semiconductor device, comprising:
- introducing a first impurity into a predetermined position of a semiconducting
material substrate or a semiconducting material layer, to obtain a semiconducting material
substrate having an impurity precipitation region or a semiconducting material layer having
an impurity precipitation region; and
- performing high selectivity anisotropic etching of said semiconducting material

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